# Electron-beam, X-ray, EUV, and ion-beam submicrometer lithographies for manufacturing VI - 11-13 March 1996, Santa Clara, California

## SPIE - Electron Beam & X

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### standard soft lithography: Topics by Science.gov

However, our quantitative results probably might not be directly translated into humans, but rather need further amendments in clinical studies.

## Electron Beam & X

The editor of this book is a member of the IEEE Nanotechnology Council.

### ultraviolet lithography system: Topics by Science.gov

They are incorporated into SiCMOS see Chapter 16 memory circuits known as ferroelectric random access memories FeRAMs.

X

Finally, we also apply the CDs as a fluorescent dye.

# Electron Beam & X

Full-chip mask optimization using source optimized by SMO can generate complex masks with small variable feature size sub-resolution assist features SRAF.

### bright green

The theoretically calculated diffraction images agree very well with the observed images. A micromirrors together comprise a two-dimensional array of micromirrors.	plurality of individually addressable and rotatable
micromirrors together comprise a two-dimensional array of micromirrors.	

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